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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/879,335

Filing Date June 11, 2001

Inventor Vishnu K. Agarwal, et al Assignee Micron Technology, Inc. Group Art Unit 2813

Examiner Y. Huynh Attorney's Docket No. MI22-1568

Title: Capacitor Forming Methods

## **RESPONSE TO APRIL 1, 2002 OFFICE ACTION**

To:

**Box Non Fee Amendment** 

Art Unit 2813

**Assistant Commissioner for Patents** 

Washington, D.C. 20231

From:

(y)

James E. Lake (Tel. 509-624-4276; Fax 509-838-3424)

Wells, St. John, Roberts, Gregory & Matkin P.S.

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## **AMENDMENTS**

## In the Specification

Please replace the title with the following clean replacement title in accordance with 37 C.F.R. § 1.121(b)(1)(ii):

V--Capacitor Forming Methods--

Please replace the paragraph beginning at line 4 of page 1 with the following clean replacement paragraph in accordance with 37 C.F.R. § 1.121(b)(1)(ii):

--This patent resulted from a continuation-in-part application of U.S. Patent Application Serial No. 09/710,546, filed on November 8, 2000, entitled "Semiconductor Processing Method" and naming Kunal R. Parekh and Randhir P.S. Thakur as inventors, which application is a continuation application of U.S. Patent No. 6,165,833, filed on December 19, 1997, each of which are herein incorporated by reference.--

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